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Characterisation and TCAD Simulation Results of Stitched Passive CMOS Strip Sensors

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22 February 2024, TREDI 2024, Torino



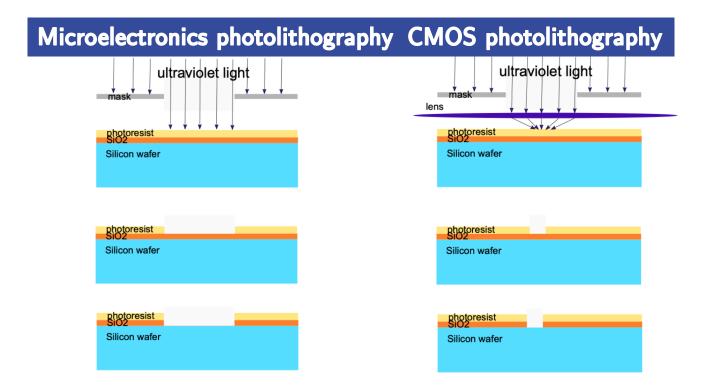
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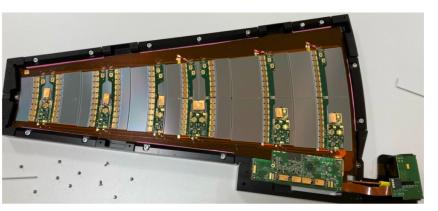
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Motivation

All the ATLAS and CMS upgrade strip detectors are being fabricated by Hamamatsu Photonics Current large area strip sensors made only by microelectronics foundries

Our goal is to show that large strip detectors can be fabricated using CMOS technology with no negative impact on their performance





Example of ATLAS ITk end-cap petal made of large area silicon strip sensors.

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Passive CMOS Strips

Sensors fabricated in LFoundry in a 150 nm process

 $\mathsf{Passive} \to \mathsf{no} \ \mathsf{electronics} \ \mathsf{included}$

 $150~\mu m$ thick silicon wafer

- Two lengths of strips 2.1 and 4.1 cm
 - 1 cm² reticle used \rightarrow strips had to be stitched

Up to five stitches in each sensor

Three different designs

- **Regular** similar to the ATLAS strip design
- Low dose 30 & 55 low dose implant and NIM capacitor

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		is)
1 cm2 reticle		

Reticle A	Reticle B	Reticle B	Reticle B	Reticle C
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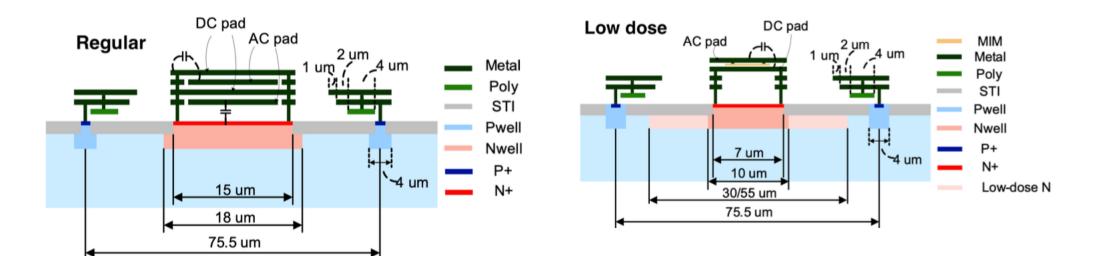
Simulations of CMOS Strips Using Sentaurus TCAD

Done in order to investigate our silicon structures in detail

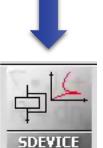
Both the fabrication process and electrical characteristics were simulated

All three designs simulated as $1~\mu m$ long strip segment

Results scaled in order to be comparable to the measurements







Electrical Characterization Detail of the Electric Field at 100 V

40 Υ [μm]

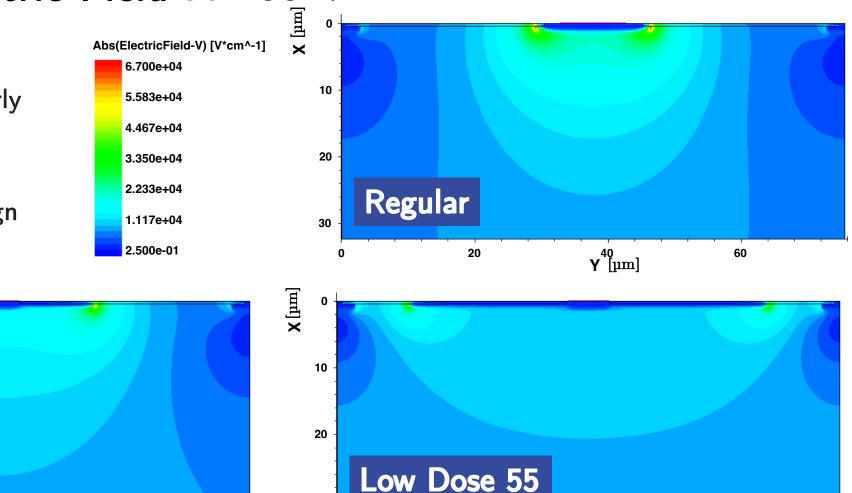
60

The difference between the individual designs clearly observable

All the characteristics were studied for each design separately

Low Dose 30

20



20

Υ⁴⁰ [μm]

60

X [µm]

10

20

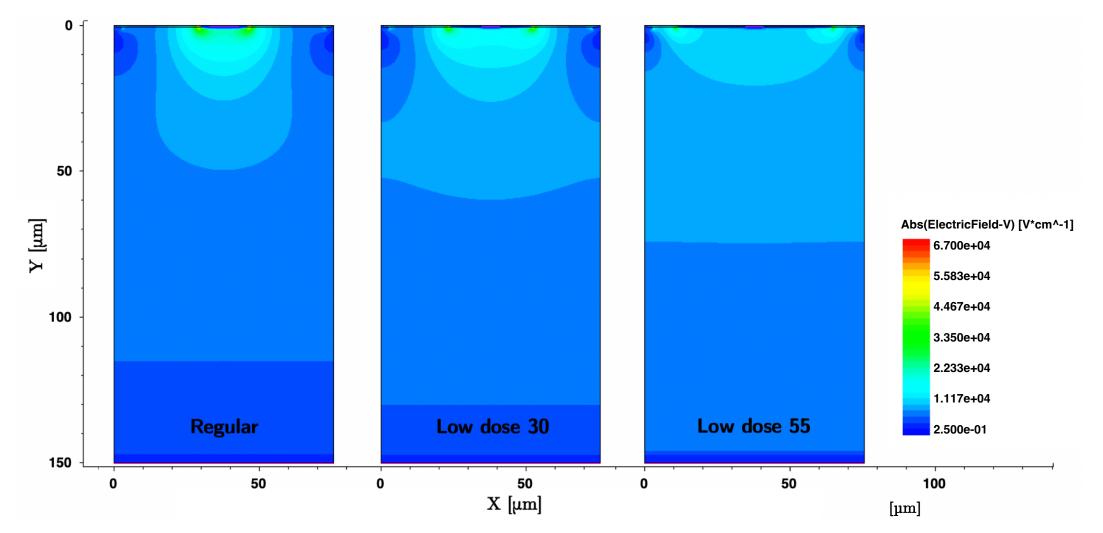
30

0

30

n

Electrical Characterization Electric Field at 100 V

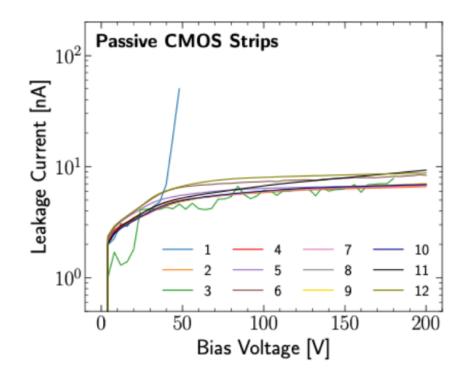


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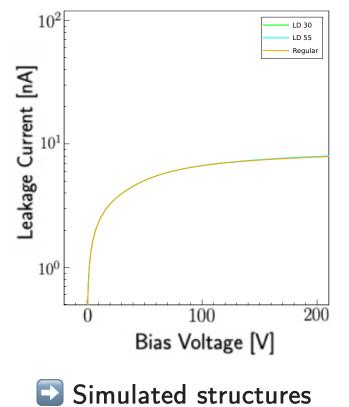
Electrical Characterization Macroscopic Characteristics

IV Measurements



Good agreement of measured values and results of the simulations

Simulations of Leakage Current

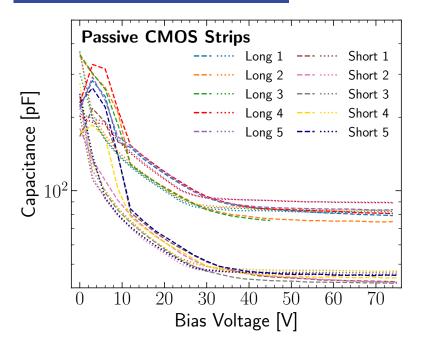


describe the real ones well

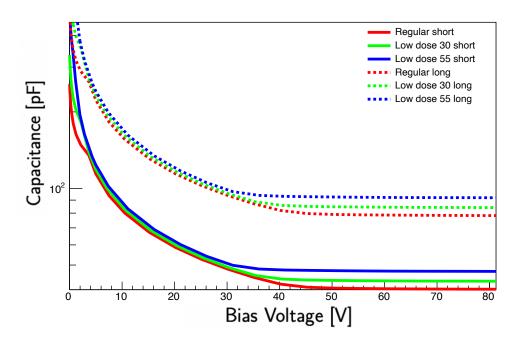
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Electrical Characterization Macroscopic Characteristics

CV Measurements



Simulations of Bulk Capacitance



Very good agreement of measured values and results of the simulations

Short strips (2.1 cm) – $C_{\text{bulk}} \approx 50 \text{ pF}$ Long strips (4.1 cm) – $C_{\text{bulk}} \approx 100 \text{ pF}$

Radiation Models in TCAD Leakage Current after Irradiation

Measurements

10

10

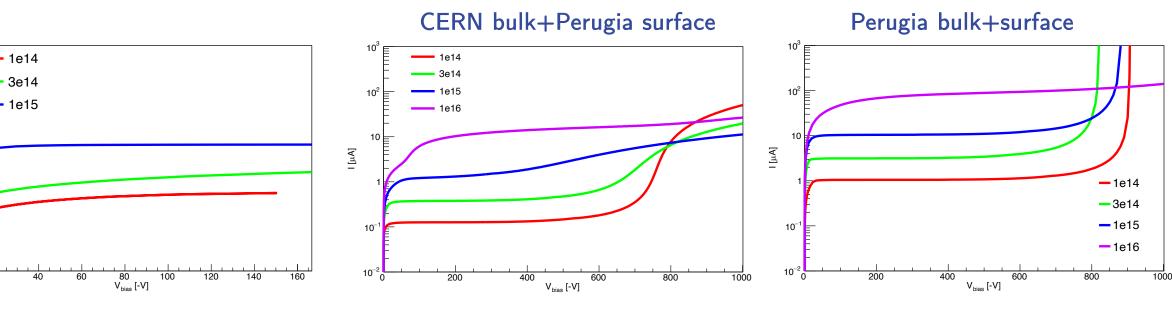
10

10

 10^{-2}

[μμ]

Simulations



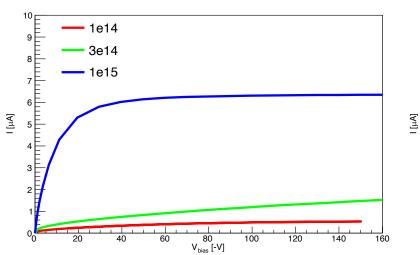
All measurements and simulation plotted for LD 30 long strips (4.1 cm)

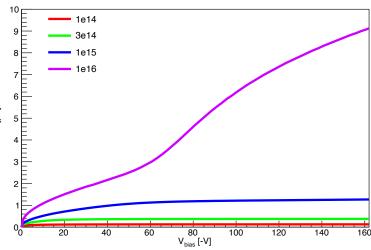
CERN model underestimates measured currents by factor of 2 Currents are overestimated by the Perugia model

Radiation Models in TCAD Leakage Current after Irradiation

Measurements

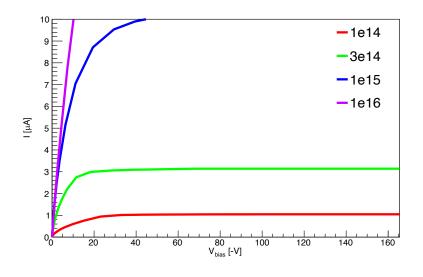
Simulations





CERN bulk+Perugia surface

Perugia bulk+surface



All measurements and simulation plotted for LD 30 long strips (4.1 cm)

CERN model underestimates measured currents by factor of 2 Currents are overestimated by the Perugia model

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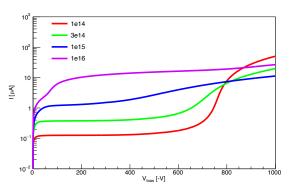
Radiation Models in TCAD Leakage Current after Irradiation

Current values @ 100 V for LD 30 long strips (4.1 cm)

Fluence $[n_{eq}/cm^2]$	Measurement	CERN model	Perugia model
$1 \cdot 10^{14}$	~ 0.5 µA	~ 0.1 µA	~ 1 µA
3.10^{14}	~ 1.5 µA	~ 0.4 µA	~ 3 µA
$1 \cdot 10^{15}$	~ 2.5 µA	~ 1.2 µA	~ 10.4 µA
$1 \cdot 10^{16}$		~ 6.2 µA	~ 47.8 µA

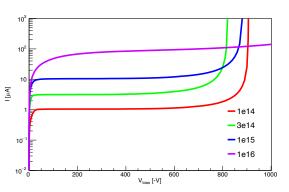
Measurement 10³ 1014 10² 1014 10³ 101 10¹ 1015 10 10² 10² 10² 10² 10² 120 140 160

CERN bulk+Perugia surface



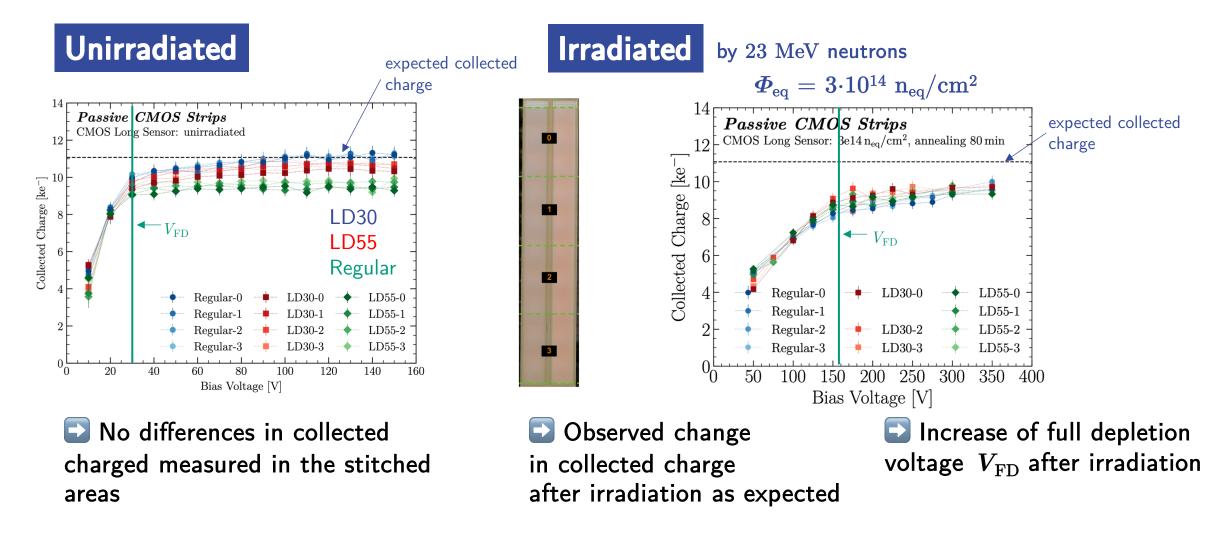
Perugia bulk+surface

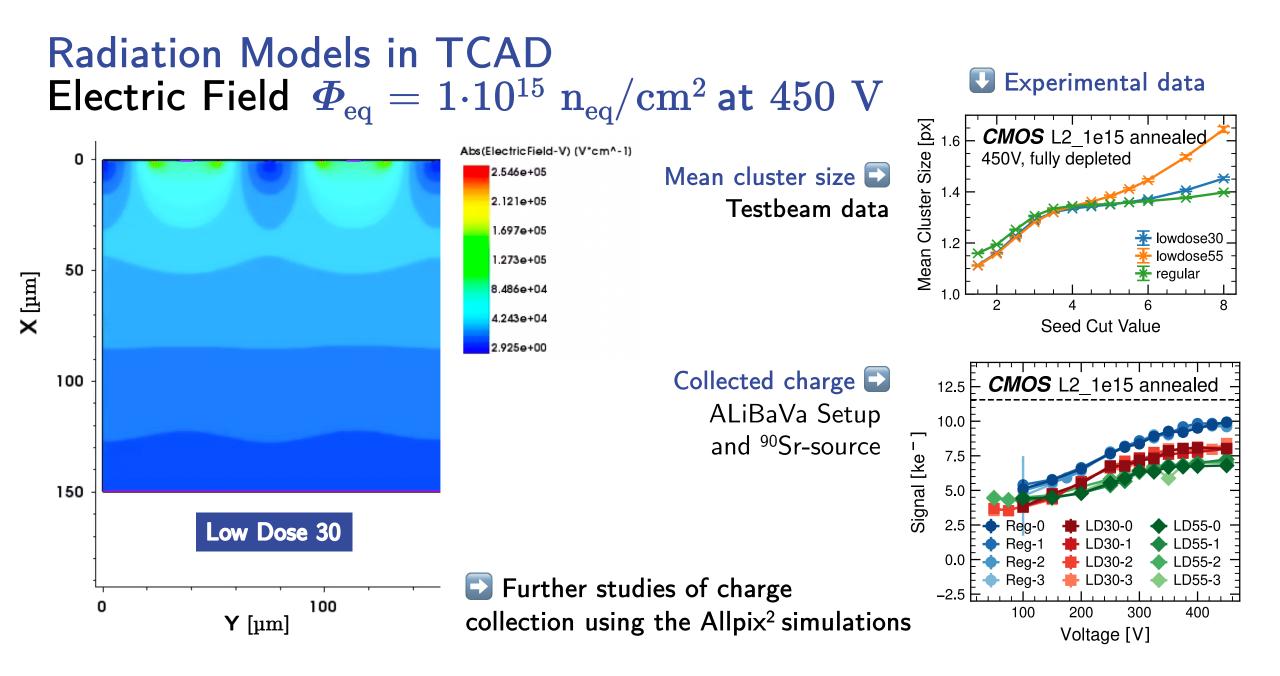
CERN model underestimates measured currents by factor of 2 Measured currents are overestimated by the Perugia model



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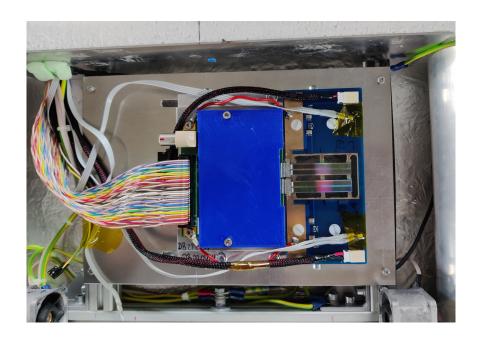
Determination of Collected Charge Using the ALiBaVa Setup and ⁹⁰Sr-source

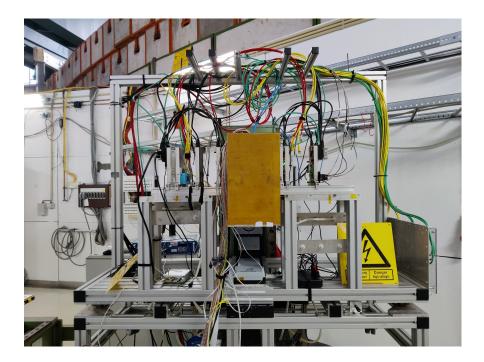


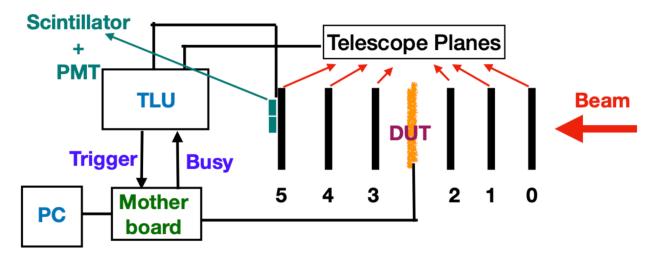


Testbeam Campaigns Done at DESY

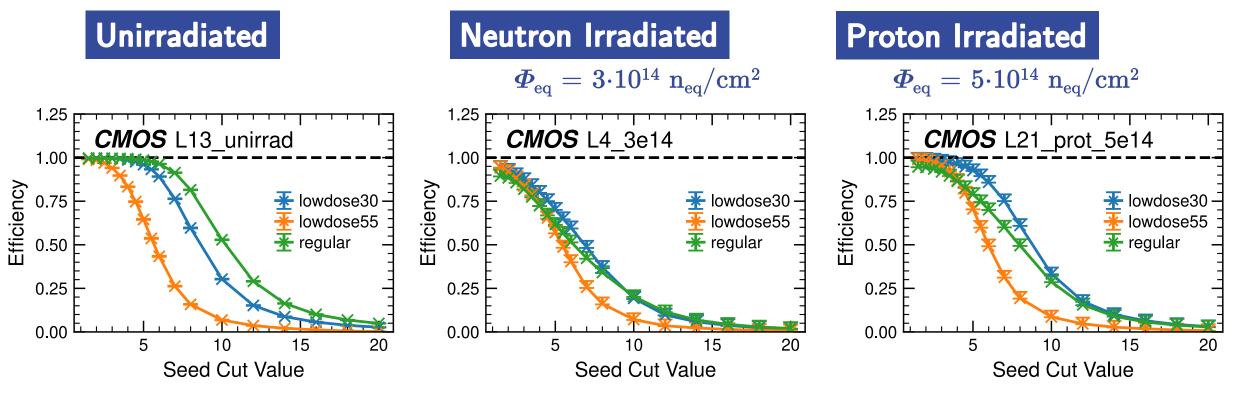
- Several testbeam campaigns took place at DESY
- Electron beam energies 3.4 and $4.2~{\rm GeV}$
- Data acquisition using ALiBaVa setup





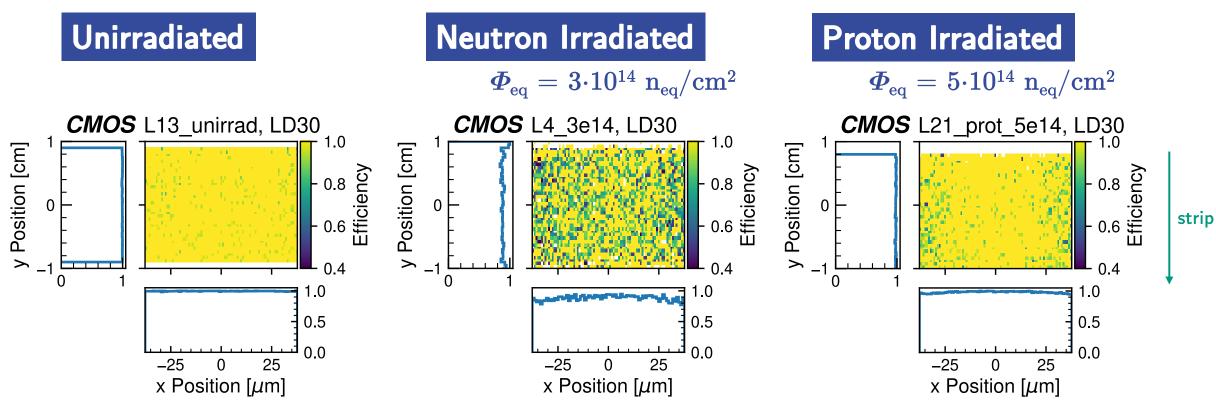


Testbeam Results Efficiency



Expected shape of the dependence of efficiency on signal/noise cut value Clear deterioration in efficiency after irradiation Efficiency of proton irradiated sensor higher than the one of neutron irradiated sensor

Testbeam Results In-strip Efficiency of Irradiated Sensors



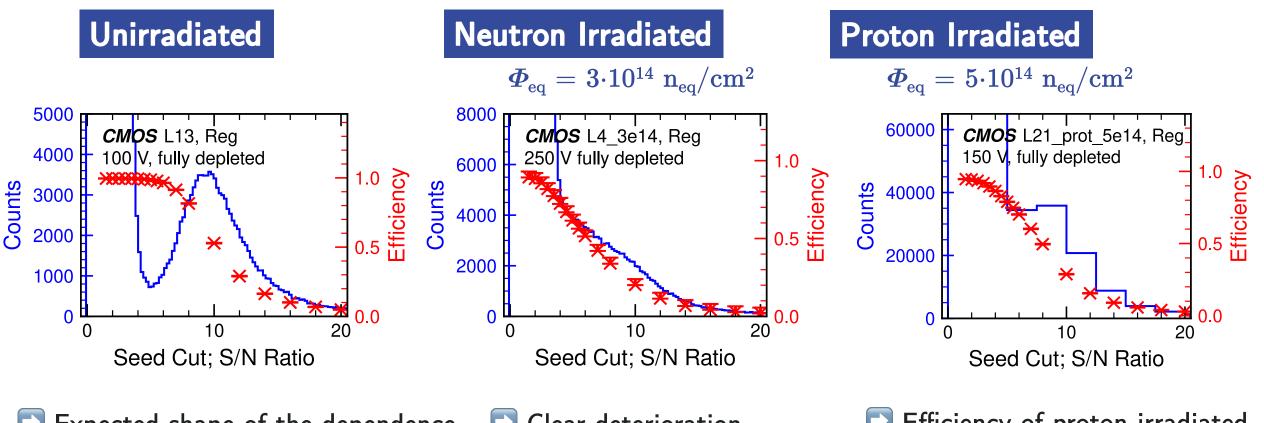
No change in efficiency observed due to the stitches

Efficiency of proton irradiated sensor higher than the one of neutron irradiated sensor

Conclusions and Outlook

- Passive CMOS strip sensors fabricated in LFoundry in a 150 nm process
- Up to 5 stitches used to achieve 2.1 and 4.1 cm strip lengths
- Electrical characteristics measured and investigated by TCAD simulations
- Several testbeam campaigns carried out in order to evaluate charge collection efficiency
- No effect of stitching on the performance of the strip detectors before and after neutron and proton irradiation was observed
- Design of the new sensors with implemented electronics in progress

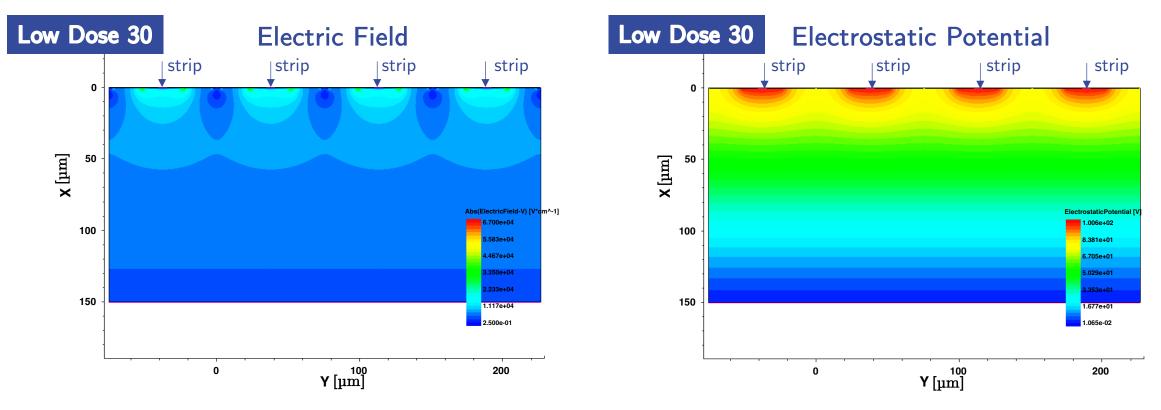
Testbeam Results Efficiency



Expected shape of the dependence of efficiency on signal/noise cut value Clear deterioration in efficiency after irradiation Efficiency of proton irradiated sensor higher than the of neutron irradiated sensor

Electrical Characterization Microscopic Characteristics at 100 V

- CMOS strip sensor simulated as a 4-strip structure
- enables to study effects of neighbouring strips e.g. during the charge collection

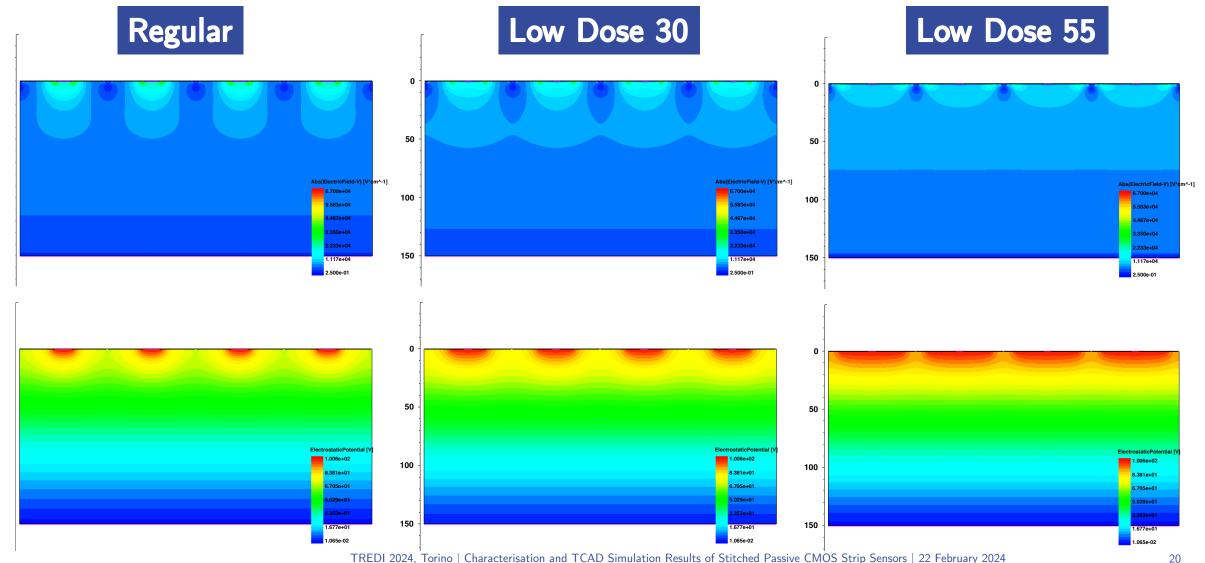


Electrical Characterization Microscopic Characteristics at 100 V

Electric Field

Potential

Electrostatic

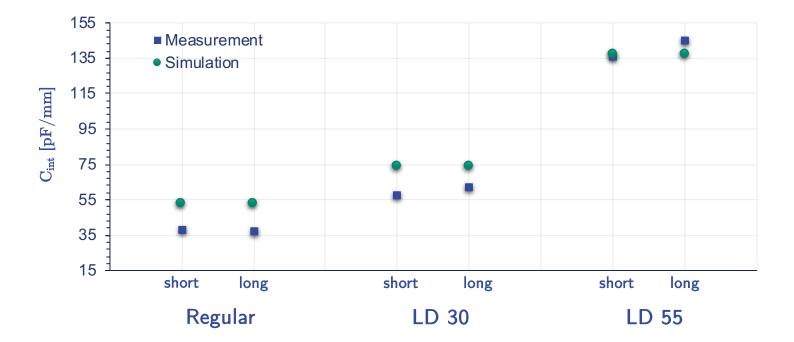


Electrical Characterization Macroscopic Characteristics

Interstrip Capacitance

 $C_{int} @ 500 kHz$

Capacitance values are means of measured/simulated values between $50\ \mathrm{V}$ and $80\ \mathrm{V}$

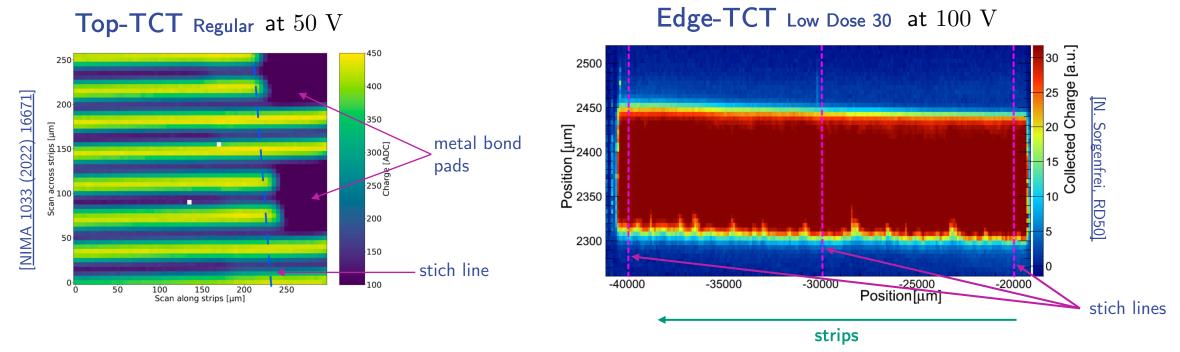


Good agreement of measured values and results of the simulations

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Transient Current Technique Measurements Top- and Edge-TCT

• Collected charge as a function of the laser position



Results of both the Top- and Edge-TCT measurements show homogenous charge collection No effect of stitching observed

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